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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of:
HARUHITO ONO ET AL.

Application No.: 10/615,955

Filed: July 10, 2003

For: MULTI-CHARGED BEAM LENS,
CHARGED-PARTICLE BEAM
EXPOSURE APPARATUS
USING THE SAME, AND
DEVICE MANUFACTURING
METHOD

Examiner: J.D. Lee

Group Art Unit: 2874

April 18, 2005

MAIL STOP
Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

RESPONSE TO RESTRICTION REQUIREMENT

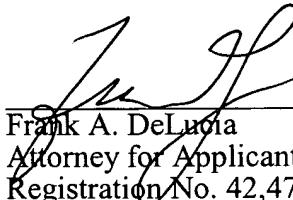
Sir:

In response to the Office Action dated March 25, 2005, Applicants elect, without traverse, to proceed initially with examination of Group I (Claims 1-19).

Applicants respectfully request favorable consideration on the merits and early passage to issue of the elected claims.

Applicants' undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our below listed address.

Respectfully submitted,



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Registration No. 42,476

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